

ABSTRACT OF THE DISCLOSURE

Disclosed is a method for manufacturing a magnetic field detecting element, capable of simplifying the manufacturing process and providing a thin-type magnetic field detecting element.

The disclosed method for manufacturing a magnetic field detecting element according to the present invention, is characterized in forming a seed film on the semiconductor substrate, then partially removing the seed film using a predetermined pattern in advance, for insulation of a plurality of coil lines that would be formed on the seed film, forming a soft magnetic core, and cutting off edges of the semiconductor substrate so that a plurality of the coil lines may be insulated.